

CLAIMS:

1. Pneumatic etching apparatus comprising:
means for entraining abrasive particles in a first part of a gas flow and
5 propelling them against a surface to be etched; and
means for drawing spent particles and debris away from said surface, wherein
said drawing means is powered by a second part of said gas flow.
2. Apparatus as claimed in claim 1, further comprising a shroud for containing
10 said abrasive particles wherein said means for drawing spent particles away from said
surface comprises a nozzle directing a gas flow away from said surface, thereby
causing a reduced pressure within the shroud.
3. Apparatus as claimed in claim 2, wherein said gas flow is directed to an
15 exhaust port via a convergent chamber communicating with the volume defined by
the shroud.
4. Apparatus as claimed in either claim 2 or claim 3 further comprising means
for allowing atmospheric air to enter said shroud close to said surface.
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5. Apparatus as claimed in any one of claims 1 to 4, wherein said means for
entraining said abrasive particles comprises:
a mixing chamber into which the gas flow draws the abrasive particles; and
a convergent-divergent blasting nozzle.
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6. Apparatus as claimed in claim 5, wherein said blasting nozzle and the side
walls of said mixing chamber form a single replaceable unit.
7. Apparatus as claimed in either claim 5 or claim 6, wherein said abrasive
30 particles enter the mixing chamber via a path in a plane substantially perpendicular to
the axis of the convergent divergent nozzle.

8. Apparatus as claimed in claim 7, wherein said path is formed from a channel on the outside of the mixing chamber wall.
- 5 9. Apparatus as claimed in any one of claims 1 to 8 further comprising a hopper for storing abrasive particles, said hopper including a particle outlet for providing abrasive particles to said means for entrainment and a particle inlet for receiving spent abrasive particles.
- 10 10. Apparatus as claimed in claim 9 wherein said particle outlet is supplied with particles via a valve biased by a spring and a gas flow in the particle inlet.